AMENDMENTS TO THE CLAIMS

This listing of claims replaces all prior versions of claims in the application.

1-12 (Cancelled)

13. (New) A susceptor of an approximately round disk shape, having a concave wafer pocket on a front surface thereof for accommodating a wafer, comprising:

a gas supply channel; and

a gas discharge channel, wherein

said gas supply channel comprises a first aperture passing through from a rear surface of the susceptor to the wafer pocket; and a groove formed from a rear-surface-side opening of the first aperture to a peripheral end of the susceptor, the groove being defined at least by an inner end and an outer end, and

the gas discharge channel comprises a second aperture passing through from the rear surface of the susceptor to the wafer pocket,

wherein a middle point of the outer end of the groove is located forward to a middle point of the inner end of the groove with respect to a rotating direction of the susceptor.

14. (New) The susceptor according to claim 13,

wherein the groove is curved in a rotating direction of the susceptor, when viewed from the inner end defining the groove.

15. (New) The susceptor according to claim 13,

wherein a wafer-pocket-side of the first aperture is inwardly defined when viewed from the rear-surface-side opening of the first aperture.

16. (New) The susceptor according to claim 13,

wherein a cross-sectional shape of the groove narrows from the outer end to the inner end of the groove.

17. (New) A susceptor of an approximately round disk shape, having a concave wafer pocket on a front surface thereof for accommodating a wafer, comprising:

a gas supply channel which comprises a first aperture passing through from a rear surface of the susceptor to the wafer pocket, and a first groove formed from a rear-surface-side opening of the first aperture to a peripheral end of the susceptor, the first groove being defined at least by an inner end and an outer end; and

a gas discharge channel comprising a second aperture passing through from the rear surface of the susceptor to the wafer pocket, and a second groove formed from the rear-surface-

side opening of the second aperture to a peripheral end of the susceptor, the second groove being defined at least by an inner end and an outer end,

wherein a middle point of the outer end of the first groove is located forward to a middle point of the inner end of the first groove with respect to a rotating direction of the susceptor, and

wherein a middle point of the outer end of the second groove is located backward to a middle point of the inner end of the second groove with respect to a rotating direction of the susceptor.

18. (New) The susceptor according to claim 17,

wherein the first groove is curved in a rotating direction of the susceptor, when viewed from the inner end defining the first groove, and the second groove is curved in a direction opposite to the rotating direction of the susceptor, when viewed from the inner end defining the second groove.

19. (New) The susceptor according to claim 17,

wherein a wafer-pocket-side of the first and second apertures are inwardly defined when viewed from the rear-surface-side openings of the apertures.

20. (New) The susceptor according to claim 17,

wherein cross-sectional shape of the fist groove narrows from the outer end to the inner end of the first groove, and

wherein cross-sectional shape of the second groove narrows from the outer end to the inner end of the second groove.